

United States Patent [35]

Harshfield

[11] Patent Number: 5,818,749

[45] Date of Patent: Oct. 6, 1998

[54] INTEGRATED CIRCUIT MEMORY DEVICE

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[73] Assignee: Micron Technology, Inc., Boise, ID

[21] Appl. No.: 884,844

[22] Filed: Feb. 24, 1997

Related U.S. Application Data

[63] Continuation-in-part of Ser. No. 348,647, Dec. 1, 1994, Pat. No. 5,646,879, which is a continuation of Ser. No. 1,02,036, Aug. 10, 1993, Pat. No. 5,379,290.

[51] Int. Cl.⁷ G11C 17/06

[52] U.S. Cl. 365/105; 365/175; 365/225.7

[58] Field of Search 365/105, 64, 175, 365/225.7, 257/225, 530

References Cited

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5,157,661 12/1992 Orshinsky et al. 365/1055,286,718 3/1994 Orshinsky et al. 357/0
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Attorney, Agent, or Firm—Fitzpatrick, Yocum & Edwards

[57] ABSTRACT

A memory array using structure changing memory elements in a reverse biased diode array is disclosed. A memory cell is programmed and read by reverse biasing the diode to overcome the diode's breakdown voltage. The disclosed reverse biased diode array exhibits much less reverse current leakage than a similar forward biased diode array.

47 Claims, 8 Drawing Sheets

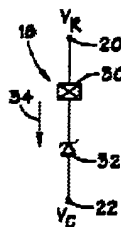
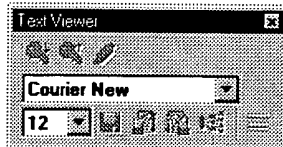


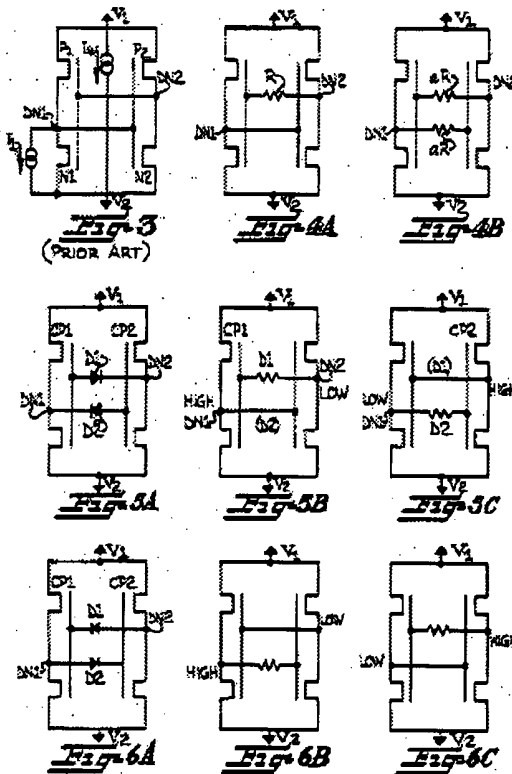
Fig 3



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	U	1	Document ID	Issue Date	Pages	Title	Current OR	Current XRef	R
12	<input type="checkbox"/>	<input type="checkbox"/>	US 20020141233 A1	20021003	30	Semiconductor memory device including memory cell	365/158		
13	<input type="checkbox"/>	<input type="checkbox"/>	US 20020140051 A1	20021003	19	Three-dimensional memory array and method of	257/530		
14	<input type="checkbox"/>	<input type="checkbox"/>	US 20020110021 A1	20020815	21	Non-volatile semiconductor memory device having	365/185.21		
15	<input type="checkbox"/>	<input type="checkbox"/>	US 20020106838 A1	20020808	26	Formation of antifuse structure in a three	438/131	257/209; 438/128	
16	<input type="checkbox"/>	<input type="checkbox"/>	US 20020088998 A1	20020711	19	THREE-DIMENSIONAL MEMORY ARRAY AND METHOD OF	257/202		
17	<input type="checkbox"/>	<input type="checkbox"/>	US 20020081851 A1	20020627	21	METHOD OF FORMING NONVOLATILE MEMORY DEVICE	438/690		
18	<input type="checkbox"/>	<input type="checkbox"/>	US 20020081782 A1	20020627	23	Contact and via structure and method of fabrication	438/131	438/637; 438/640	
19	<input type="checkbox"/>	<input type="checkbox"/>	US 20020081753 A1	20020627	12	Formation of arrays of microelectronic elements	438/3		
20	<input type="checkbox"/>	<input type="checkbox"/>	US 20020079553 A1	20020627	22	Contact and via structure and method of fabrication	257/530	257/774; 257/775;	
21	<input type="checkbox"/>	<input type="checkbox"/>	US 20020075719 A1	20020620	14	Low-cost three-dimensional memory array	365/130		
22	<input type="checkbox"/>	<input type="checkbox"/>	US 20020050606 A1	20020502	57	SEMI-MONOLITHIC MEMORY WITH HIGH-DENSITY CELL	257/202	257/827.075	



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	U	1	Document ID	Issue Date	Pages	Title	Current OR	Current XRef R
23	<input type="checkbox"/>	<input type="checkbox"/>	US 20020028541 A1	20020307	151	Dense arrays and charge storage devices, and methods	438/149	257/E29.129; 257/E29.302;
24	<input type="checkbox"/>	<input type="checkbox"/>	US 20020027793 A1	20020307	41	Vertically stacked field programmable nonvolatile	365/103	257/E27.073
25	<input type="checkbox"/>	<input type="checkbox"/>	US 20020018355 A1	20020214	41	Vertically stacked field programmable nonvolatile	365/103	257/E27.073
26	<input type="checkbox"/>	<input type="checkbox"/>	US 20010055838 A1	20011227	28	Nonvolatile memory on SOI and compound semiconductor	438/129	
27	<input type="checkbox"/>	<input type="checkbox"/>	US 20010048608 A1	20011206	21	Magnetic random access memory circuit	365/158	
28	<input type="checkbox"/>	<input type="checkbox"/>	US 20010010938 A1	20010802	15	Diode connected to a magnetic tunnel junction and	438/3	438/246; 438/248;
29	<input type="checkbox"/>	<input type="checkbox"/>	US 6541312 B2	20030401	24	Formation of antifuse structure in a three	438/131	365/159; 365/175
30	<input type="checkbox"/>	<input type="checkbox"/>	US 6534403 B2	20030318	21	Method of making a contact and via structure	438/666	438/625; 438/669;
31	<input type="checkbox"/>	<input type="checkbox"/>	US 6515897 B1	20030204	16	Magnetic random access memory using a non-linear	365/173	365/145; 365/171
32	<input type="checkbox"/>	<input type="checkbox"/>	US 6515888 B2	20030204	14	Low cost three-dimensional memory array	365/130	365/105; 365/113;
33	<input type="checkbox"/>	<input type="checkbox"/>	US 6504761 B2	20030107	21	Non-volatile semiconductor memory device improved sense	365/185.21	365/189.07; 365/203

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